Supporting Information

Influence of surfactants in forced dynamic dewetting

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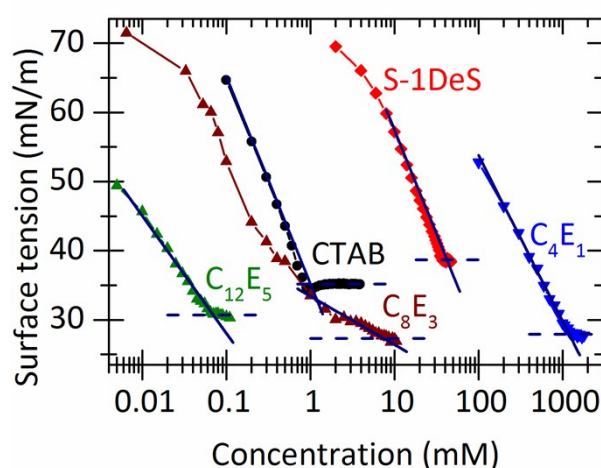
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Figure S1: Surface tension γ versus log of concentration c for the surfactants used. The minimum observed with CTAB is most likely due to trace amounts of contamination. The CMCs were determined where the respective red lines cross each other. One represents the plateau surface tension γ^* (dashed), on represents a linear fit to the decreasing part according to $\gamma(c) = \gamma^* - \alpha\left(\log c - \log CMC\right)$, with α and the CMC as fit parameters.
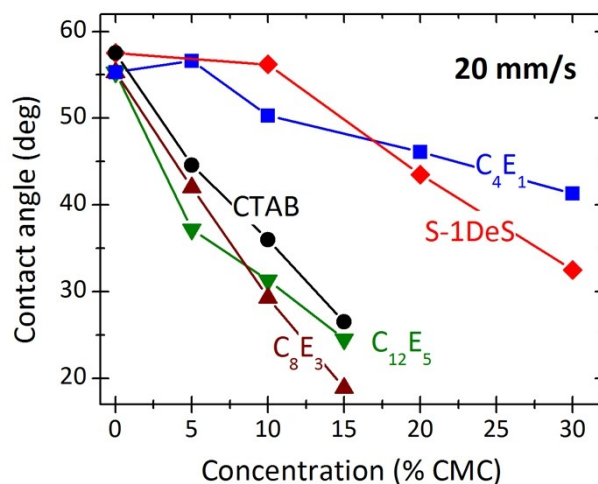
Figure S2. Dynamic receding contact angles at a velocity of 20 mm/s versus surfactant concentration, for all surfactants used. Surfactant concentrations are given in percentages of the CMC.
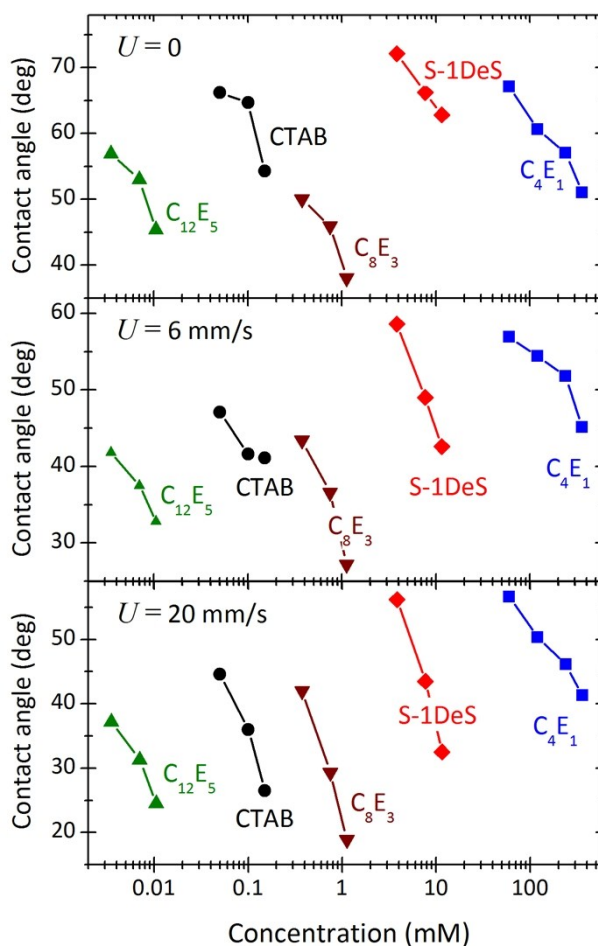

Figure S3. Dynamic receding contact angles at zero velocity and at 6 and 20 mm/s versus surfactant concentration, for all surfactants used. Surfactant concentrations are given mM. The points at zero concentration were omitted because of the logarithmic scale.